

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10580036
<b>Filing Date:</b>	19-May-2006
<b>Title of Invention:</b>	Plasma processing method and plasma processing apparatus
<b>First Named Inventor/Applicant Name:</b>	Yasuo Kobayashi
<b>Filer:</b>	Marvin Jay Spivak/Yuriko Stankich
<b>Attorney Docket Number:</b>	291327US26PCT

Filed as Large Entity

### **U.S. National Stage under 35 USC 371 Filing Fees**

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
<b>Post-Allowance-and-Post-Issuance:</b>				
<b>Extension-of-Time:</b>				
Extension - 2 months with \$0 paid	1252	1	490	490

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Miscellaneous:</b>				
<b>Total in USD (\$)</b>				<b>490</b>